



Att. Docket No. 10191/1690

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Appl. Serial No. : 09/762,985 Confirmation No. 2674  
Title : DEVICE AND METHOD FOR  
ETCHING A SUBSTRATE USING  
AN INDUCTIVELY COUPLED PLASMA  
Applicant(s) : Volker BECKER et al.  
Filed : May 8, 2001  
TC/A.U. : 1763  
Examiner : Luz L Alejandro Mulero  
Docket No. : 10191/1690  
Customer No. : 26646

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

hereby certify that this correspondence is being deposited with the  
United States Postal Service with sufficient postage as first class mail  
in an envelope addressed to:  
Mail Stop AF  
Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450  
on

Date: 12/14/2004

Signature: [Signature]

AARON C. DEDITCH  
(33,865)

**AMENDMENT AFTER A FINAL OFFICE ACTION**

S I R:

In response to the Final Office Action mailed on September 29, 2004 (the three-month response date for which is December 29, 2004), please reconsider the above-identified application based on the following:

**Amendments to the Claims** are reflected in the listing of the claims which begins on page 2 of this paper.

**Remarks** begin on page 9 of this paper.

*Express Mail No. EV 047805377 US*